

N THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Tadahiro OHMI, et al.

Title:

ELECTRON BEAM EXPOSURE APPARATUS AND

EXPOSURE METHOD

Appl. No.:

10/567,828

Filing Date:

4/28/2006

Examiner:

Christopher G. Young

Art Unit:

1795

Confirmation No.:

2084

AMENDMENT AND REPLY UNDER 37 C.F.R. 1.111

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

This communication is responsive to the Non-Final Office Action dated March 11, 2009, concerning the above-referenced patent application.

Applicants have enclosed with this amendment a Petition for Extension of Time for three months to make this response timely.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this document.

Remarks/Arguments begin on page 5 of this document.

Please amend the application as follows: